Claims

1. An alignment assembly for aligning a plurality of IC units, the assembly comprising:

a plate having vacuum apertures for receiving said IC units on an engagement surface;

a first alignment member having a plurality of projections and recesses uniformly distributed along a first engagement edge;

a second alignment member having a plurality of projections and recesses uniformly distributed along a second engagement edge;

said first and second alignment members in sliding contact with the engagement surface;

wherein said first and second alignment members arranged to move relative to each other so as to intermesh said respective projections and recesses, said intermeshed projections and recesses arranged to define a linear array of rectangular apertures sized to fit said IC units in an aligned condition, and wherein

at least one of said alignment members having a follower in resilient contact with a cam, the cam is arranged such that on rotation of said cam, the relative movement of said alignment members is along a path inclined to an axis of said linear array so as to move at least one plate from a distal position whereby the plates are separated to an intermesh position whereby the projections and recesses are intermeshed.

2. The alignment assembly according to any one of claim 1, wherein said projections and recesses include alignment faces arranged contact and bias misaligned IC units so as to place said misaligned IC units into the aligned condition.

3. A method for aligning a linear array of IC units, the method comprising the steps of:

providing first and second alignment members in sliding contact with a surface, said members having projections and recesses along respective first and second engagement edges;

placing said IC units on the surface intermediate the engagement edges;

relatively moving first and/or second alignment members from a distal position and to an intermesh position, and so intermeshing said respective projections and recesses;

rotating at least one cam, said at least one cam in contact with at least one follower mounted to the first alignment member;

moving said follower by said cam rotation and so moving the first alignment member, wherein the cam is arranged such that on rotation of said cam, the relative movement of said alignment members is along a path inclined to an axis of said linear array;

said intermeshed projections and recesses surrounding said placed IC units, and;

aligning said IC units within rectangular apertures defined by the intermeshed projections and recesses.

4. The method according to claim 3 wherein the relatively moving step includes the steps of:

rotating a first and second cam, said cams in contact with followers respectively mounted to the first and second alignment members;

moving said followers by said cam rotation and so moving the first and second alignment members.